

### **Amendments to the Specification:**

*Please amend the paragraph beginning on page 1, at lines 4-8 as shown below:*

#### **CROSS-REFERENCE TO RELATED APPLICATIONS**

This application is a continuation of application Serial No. 09/938,358 filed on August 23, 2001, now U.S. Patent No. 6,628,177 which claims the benefits of U.S. provisional patent applications Serial No. 60/227,505 filed August 24, 2000 and entitled "Micromechanical Disk Resonators" and Serial No. 60/227,507 also filed August 24, 2000 and entitled "Process Technology For Lateral Small-Gap Micromechanical Structures."

*Please amend the paragraph beginning on page 13, at line 6 as shown below:*

For example, Figure 5 shows nodes 50 and an anti-node portion 52 where there is most of the motion of a higher order disk 53. Figure 6 shows electrodes 54 on a substrate 56 for sensing motion at the outer rim of the disk 53. Inner and outer electrodes 58 and 60, respectively, are positioned to sense motion of fins 62 which project upwardly from the anti-node portion 52 of the disk 53 (shown positioned closer to the rim of the disk ~~52~~ 53 than shown in Figure 5 for purposes of illustration). Rather than the electrodes 58 and 60, mechanical links may be used to obtain the output from the anti-node. Figure 6 shows the disk 53 levitated above the substrate 56 without the need for a mechanical support. Such levitation can be achieved either electrically or magnetically as previously noted.